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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Wunnicke, et al. Docket No.: INF-138  
Serial No.: 10/781,920 Art Unit: 1756  
Filed: February 20, 2004 Examiner: TBD  
For: Method for Fabricating a Resist Mask for Patterning Semiconductor Substrates

**Certificate of Mailing via First Class Mail (37 C.F.R. § 1.8(a))**

Date of Deposit: August 13, 2004

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Certificate of Mailing via First Class Mail (1 page)  
Information Disclosure Statement (1 page)  
IDS Combined Form PTO/SB/08a and 08b (1 page) citing (5) references  
Copies of (4) cited references  
Transmittal of Certified Copy of Priority Document (1 page)  
Certified Copy of DE 103 07 523.2  
Return Postcard

Respectfully submitted,

Natalie Swider  
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Mail Stop: Amendment  
Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

**INFORMATION DISCLOSURE STATEMENT**

Dear Sir:

Applicants wish to bring to the attention of the Patent and Trademark Office the information noted on the enclosed combined form PTO/SB/08a & 08b that may be considered material to the examination of the above-identified application.

No fee is due at this time, as this Information Disclosure Statement is being filed pursuant to 37 C.F.R. § 1.97(b)(3), before the mailing of a first Office action on the merits.

Respectfully submitted,

Ira S. Matsil  
Attorney for Applicants  
Reg. No. 35,272

August 13, 2004

Date

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**Transmittal of Certified Copy of Priority Document**

Dear Sir:

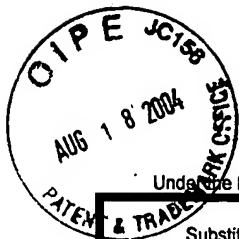
Attached please find a certified copy of the foreign application from which priority is claimed for this case:

Country: Germany  
Application Number: 103 07 523.2  
Filing Date: February 21, 2003

Respectfully submitted,

Ira S. Matsil  
Reg. No. 35,272  
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PTO/SB/08a (08-03)  
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U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Substitute for form 1449A/PTO

## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

### Complete if Known

Application Number	10/781,920
Filing Date	2/20/2004
First Named Inventor	Wunnicke, et al.
Art Unit	1756
Examiner Name	TBD
Attorney Docket Number	INF-138

Sheet	1	of	1
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### U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code <sup>2</sup> (if known)			
	1	US-4,914,006	04-03-1990	Kato, et al.	

### FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>
		Country Code <sup>3</sup> - Number <sup>4</sup> - Kind Code <sup>5</sup> (if known)				
	2	WO 02/067304 A1	08-29-2002	Hyon, Man-Sok		

### NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
	3	TANAKA, T., et al., "Mechanism of Resist Pattern Collapse during Development Process," Jpn. J. Appl. Phys. Vol. 32, Part I, No. 12B, December 1993, pp. 6059-6064.	
	4	CAO, H.B., et al., "Comparison of Resist Collapse Properties for Deep Ultraviolet and 193 nm Resist Platforms," J. Vac. Sci. Technol. B, Vol. 18, No. 6, Nov/Dec 2000, pp. 3303-3307.	
	5	DÖRFLER, H.-D., "Grenzflächen und Kolloidchemie," VCH, 1994, ISBN 3-527-29072-9, pp. 225-229	

Examiner Signature	Date Considered
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. <sup>1</sup>Applicant's unique citation designation number (optional). <sup>2</sup>See Kinds Codes of USPTO Patent Documents at [www.uspto.gov](http://www.uspto.gov) or MPEP 901.04. <sup>3</sup>Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup>For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup>Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. <sup>6</sup>Applicant is to place a check mark here if English language Translation is attached.

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